



Applicant : Fukuda et al. ) Group Art Unit 1763  
 )  
 Appl. No. : 09/511,934 )  
 )  
 Filed : February 24, 2000 )  
 )  
 For : THIN-FILM FORMING )  
 )  
 )  
 )  
 )  
 )  
 )  
 )  
 Examiner : R. Kackar )

RECEIVED  
 NOV - 4 2002  
 TC 1100 MAIL ROOM

AMENDMENT AND RESPONSE TO ADVISORY ACTION

#12C  
 11/5/02  
 MW

Assistant Commissioner for Patents  
 Washington, D.C. 20231

Dear Sir:

A request for continued examination (RCE) has been filed under 37 C.F.R. § 1.114 in the above-identified application. In response to the Advisory Action mailed October 2, 2002, please enter the AMENDMENT AFTER FINAL dated September 18, 2002, and further amend the above-captioned application as follows:

IN THE CLAIMS:

**Please cancel Claims 2-3 and 11-20 without prejudice.**

**Please amend Claim 1 as follows:**

1. (Thrice amended) A thin film forming apparatus comprising:  
 a reaction chamber for forming at a film formation temperature a thin film on a workpiece placed on a susceptor provided in the reaction chamber, said susceptor being made of aluminum nitride and provided with a heater for heating the workpiece, said reaction chamber being